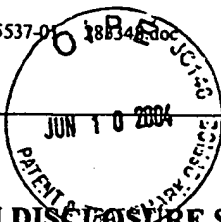


<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>				<b>Attorney Docket Number</b>	6500-65537
				<b>Application Number</b>	Not yet assigned
				<b>Filing Date</b>	Concurrently Herewith
				<b>First Named Inventor</b>	Novak
				<b>Art Unit</b>	Not yet assigned
				<b>Examiner Name</b>	Not yet assigned
<b>U.S. PATENT DOCUMENTS</b>					
<b>Examiner's Initials*</b>	<b>Cite No. (optional)</b>	<b>Number</b>	<b>Date</b>	<b>Name</b>	
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<b>EXAMINER SIGNATURE:</b> <i>RDS</i>	<b>DATE CONSIDERED:</b> 3/03/2006
* Examiner: Initial if reference considered, whether or not in conformance with MPEP 609. Draw line through cite if not in conformance and not considered. Include copy of this form with next communication to applicant.	



# **INFORMATION DISCLOSURE STATEMENT BY APPLICANT**

<b>Attorney Docket Number</b>	6500-65537-01
<b>Application Number</b>	10/765,703
<b>Filing Date</b>	January 26, 2004
<b>First Named Inventor</b>	Novak
<b>Art Unit</b>	2872
<b>Examiner Name</b>	Not yet assigned

## **FOREIGN PATENT DOCUMENTS**

Examiner's Initials*	Cite No. (optional)	Country	Number	Publication Date	Name of Applicant or Patentee
RMJ		Europe	EP 1 376 191 A1	2-Jan-2004	Nikon Corporation

**EXAMINER  
SIGNATURE:**

*RMJ*

**DATE**

**CONSIDERED:**

*3/03/2006*

\* Examiner: Initial if reference considered, whether or not in conformance with MPEP 609. Draw line through cite if not in conformance and not considered. Include copy of this form with next communication to applicant.